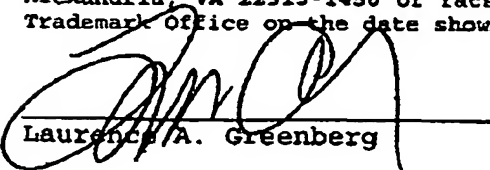


Practitioner's Docket No.: L&amp;L-I0242

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Laurence A. GreenbergJanuary 9, 2006  
DateIN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/694,593 Confirmation No.: 3503  
Applicant : Olaf Storbeck, et al.  
Filed : October 27, 2003  
Title : Method for Minimizing the Vapor  
Deposition of Tungsten Oxide During the  
Selective Side Wall Oxidation of  
Tungsten-Silicon Gates  
Art Unit : 2823  
Examiner : Fernando L. Toledo  
Customer No. : 24131

*Do not enter 1/2/06*

R E S P O N S E

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Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated October 14, 2005,  
kindly consider the following remarks:

Remarks/Arguments begin on page 2 of this paper.